

Datasheet: MakroPorP1.5M1-50

Macroporous silicon membrane (108545-W02)

Etching

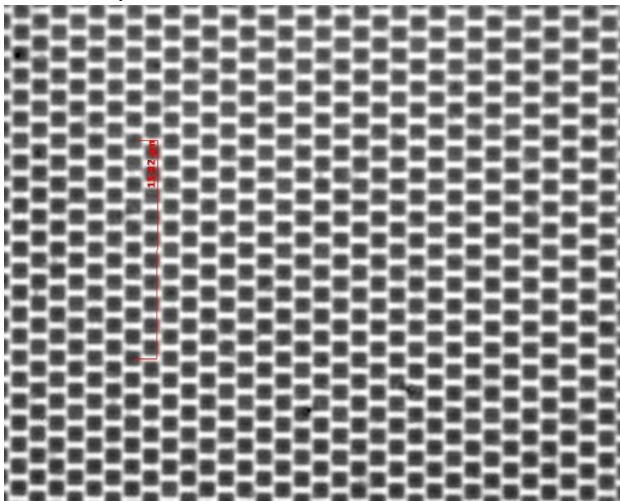
Wafer Size:	6 inch
Pitch:	1.5 μm trigonal
Pore length:	55 μm
Pore diameter:	1.0 μm

Postprocessing

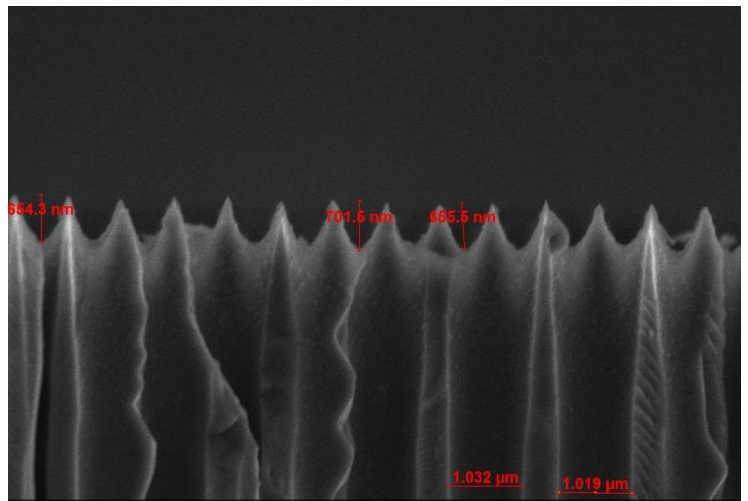
Membrane lift off
laserdicing

Images

Front Top

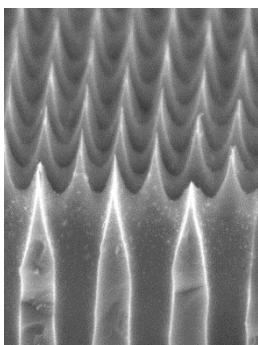


side view (REM)



Remarks

Side view (generic) (REM)



- Lifted backsides are sensitive to mechanical handling. Abrasion of silicon nanotips is visible as brown “scratches” on the surface but have minor effect on the underlying pores. **We suggest using vacuum tweezers on the front side.** Depending on the thickness, flat tips with small diameters are preferred instead of suction cup tips, to minimize mechanical Stress.

(If not specified separately standard tolerances of $\pm 10\%$ will apply)